

workshop:

Etch Tech 2012: *Pushing the Limits* **July 16-17, 2012**

Venue: *California Institute of Technology, Pasadena, CA, USA*



This workshop is open to all those people working in industry and academia, with an interest in recent progress in research and development, plus future trends in the fabrication and application of micro & nano structures and devices.

Agenda Monday, July 16

Time	Talk title	Speaker
8:30-9:00	Registration & Coffee	
9:00-9:15	Welcome & Introduction to Oxford Instruments	<i>Dan Ayres, Managing Director, Oxford Inst.</i>
9:15-9:45	Nanoscale Applications of ALD	<i>Zuwei Liu, LBNL/ Oxford Instruments</i>
9:45-10:15	Advances in Deep RIE / MEMS	<i>Michelle Bourke, Oxford Instruments</i>
10:15-10:40	Break	
10:40-11:10	Silicon Etching for Nanomechanics	<i>Oskar Painter, Co-Director KNI, Caltech</i>
11:10-11:40	III V Etch for nano device applications	<i>Bob Gunn, Oxford Instruments</i>
11:40-12:10	OpSIS Optoelectronics Systems Integration in Silicon	<i>Michael Hochberg, University of Delaware</i>
12:10-1:15	Lunch	
1:15-1:45	Single Digit Nanoscale Fabrication	<i>Deirdre Olynick, Molecular Foundry, LBNL</i>
1:45-2:15	Fabrication of Piezoelectric Nanoelectromechanical Systems	<i>Rassul Karabalin, Caltech</i>
2:15-2:45	Break	
2:45-3:15	Three Dimensional Etching of Silicon Nanostructures	<i>Sameer Walavalkar, Caltech</i>
3:15-3:45	Fabrication of micro and nano photonic devices in mono-crystalline diamond	<i>Andrei Faraon, Caltech</i>
3:45-4:00	Questions and close	<i>Oskar Painter, Co-Director KNI, Caltech</i>

Agenda Tuesday 17th July

Time	Workshop	Speaker/Facilitator
9:00 – 10:00	Plasma measurement	<i>Leslie Lea, Principal Technologist, Oxford Inst.</i>
10:00-11:00	Process recovery and cross contamination prevention	<i>Craig Ward, Applications Engineer, Oxford Inst.</i>
11:00-12:00	ALD Tutorial	<i>Annika Peter, Technologist, Oxford Instruments</i>
12:00-1:00	Lunch break	
1:00 – 3:00	KNI Caltech Lab Tours	

Subject to change.

